



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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GROUP 1700

Applicants: Shinichiro KOTAKE, et al.  
Title: FLUE GAS TREATING SYSTEM AND PROCESS  
Appl. No.: 09/658,928  
Filing Date: September 11, 2000  
Examiner: Timothy C. Vanoy  
Art Unit: 1754

**AMENDMENT AND RESPONSE UNDER 37 C.F.R. §1.111**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

This is a response to the Office Action mailed on March 11, 2003, in connection with the captioned application.

The amendments presented below comply with the revised amendment format permitted by the Notice from the Office of Patent Legal Administration of the U.S. Patent and Trademark Office dated February 10, 2003. Thus, the provisions of 37 C.F.R. § 1.121(a), (b), (c) and (d) are waived for amendments made to the claims, specification and drawings of this application.

**Amendments to the Claims** are reflected in the listing of claims beginning on page 2 of this document.

**Remarks/Arguments** begin on page 6 of this document.

Please amend the application as follows.